

Computer-Aided Design for Micro-Electro-Mechanical Systems

Eigenvalues, Energy Losses, and Dick Tracy Watches

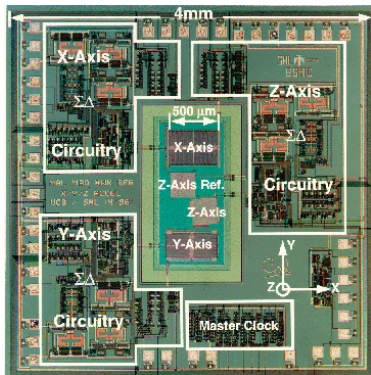
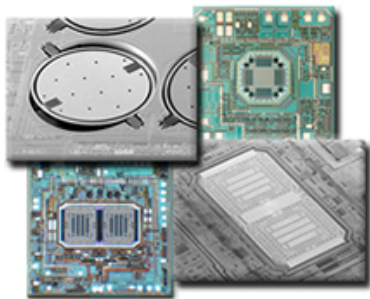
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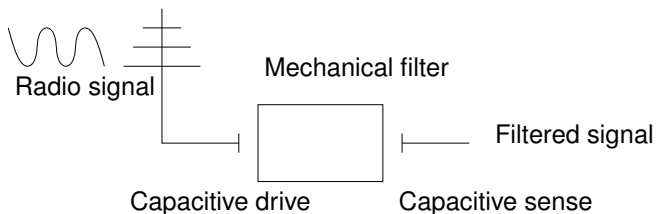
Bay Area Scientific Computing Day, 4 Mar 2006

What are MEMS?

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Micromechanical Filters



- Mechanical high-frequency (high MHz-GHz) filter
 - Your cell phone is mechanical!
 - New MEMS filters can be integrated with circuitry
 - ⇒ smaller and lower power

Ultimate Success

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“Calling Dick Tracy!”



Designing Transfer Functions

Time domain:

$$\begin{aligned}Mu'' + Cu' + Ku &= b\phi(t) \\ y(t) &= p^T u\end{aligned}$$

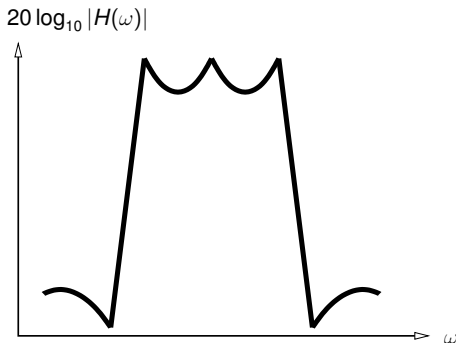
Frequency domain:

$$\begin{aligned}-\omega^2 M\hat{u} + i\omega C\hat{u} + K\hat{u} &= b\hat{\phi}(\omega) \\ \hat{y}(\omega) &= p^T \hat{u}\end{aligned}$$

Transfer function:

$$\begin{aligned}H(\omega) &= p^T (-\omega^2 M + i\omega C + K)^{-1} b \\ \hat{y}(\omega) &= H(\omega) \hat{\phi}(\omega)\end{aligned}$$

Narrowband Filter Needs



- Want “sharp” poles for narrowband filters
- \implies Want to minimize damping

Damping and Q

Designers want high *quality of resonance* (Q)

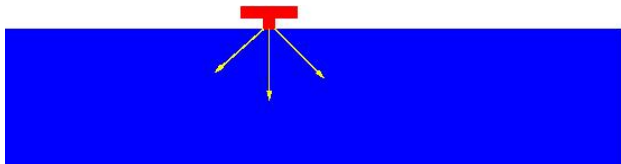
- Dimensionless damping in a one-dof system

$$\frac{d^2 u}{dt^2} + Q^{-1} \frac{du}{dt} + u = F(t)$$

- For a resonant mode with frequency $\omega \in \mathbb{C}$:

$$Q := \frac{|\omega|}{2 \operatorname{Im}(\omega)} = \frac{\text{Stored energy}}{\text{Energy loss per radian}}$$

Damping Mechanisms



Possible loss mechanisms:

- Fluid damping
- Material losses
- Thermoelastic damping
- **Anchor loss**

Model substrate as semi-infinite with a

Perfectly Matched Layer (PML).

Perfectly Matched Layers

- Complex coordinate transformation
- Generates a “perfectly matched” absorbing layer
- Idea works with general linear wave equations
 - Electromagnetics (Bereng er, 1994)
 - Quantum mechanics – *exterior complex scaling* (Simon, 1979)
 - Elasticity in standard finite element framework (Basu and Chopra, 2003)

Model Problem

- Domain: $x \in [0, \infty)$
- Governing eq:

$$\frac{\partial^2 u}{\partial x^2} - \frac{1}{c^2} \frac{\partial^2 u}{\partial t^2} = 0$$

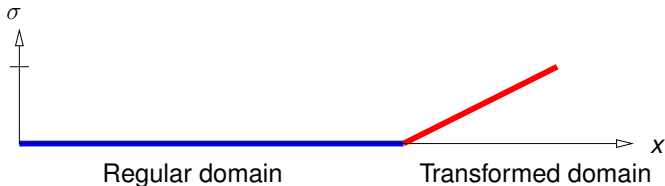
- Fourier transform:

$$\frac{d^2 \hat{u}}{dx^2} + k^2 \hat{u} = 0$$

- Solution:

$$\hat{u} = c_{\text{out}} e^{-ikx} + c_{\text{in}} e^{ikx}$$

Model with Perfectly Matched Layer

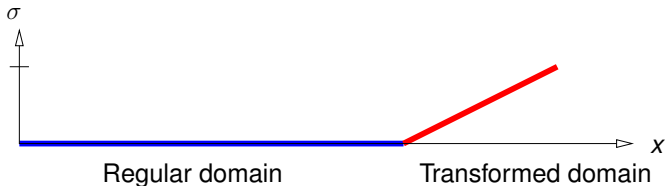


$$\frac{d\tilde{x}}{dx} = \lambda(x) \text{ where } \lambda(s) = 1 - i\sigma(s)$$

$$\frac{d^2\hat{u}}{d\tilde{x}^2} + k^2\hat{u} = 0$$

$$\hat{u} = c_{\text{out}}e^{-ik\tilde{x}} + c_{\text{in}}e^{ik\tilde{x}}$$

Model with Perfectly Matched Layer



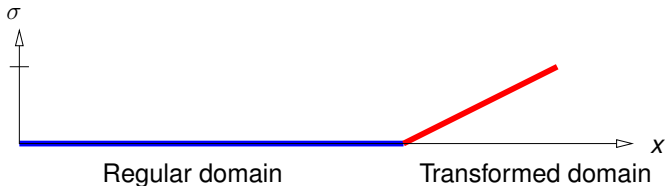
$$\frac{d\tilde{x}}{dx} = \lambda(x) \text{ where } \lambda(s) = 1 - i\sigma(s),$$

$$\frac{1}{\lambda} \frac{d}{dx} \left(\frac{1}{\lambda} \frac{d\hat{u}}{dx} \right) + k^2 \hat{u} = 0$$

$$\hat{u} = c_{\text{out}} e^{-ikx - k\Sigma(x)} + c_{\text{in}} e^{ikx + k\Sigma(x)}$$

$$\Sigma(x) = \int_0^x \sigma(s) ds$$

Model with Perfectly Matched Layer

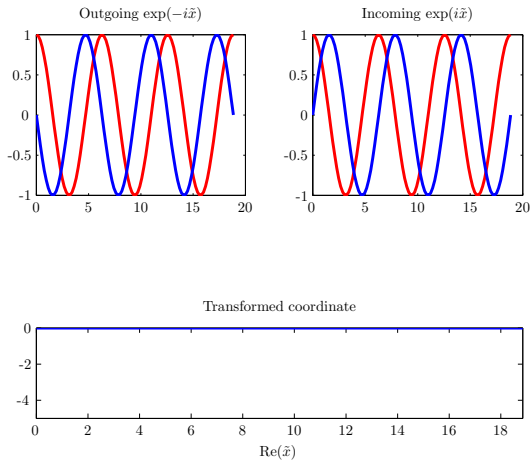


If solution clamped at $x = L$ then

$$\frac{c_{\text{in}}}{c_{\text{out}}} = O(e^{-k\gamma}) \text{ where } \gamma = \Sigma(L) = \int_0^L \sigma(s) ds$$

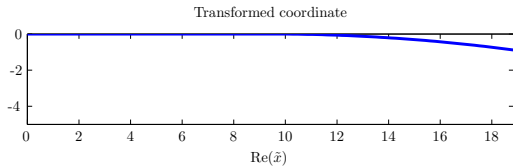
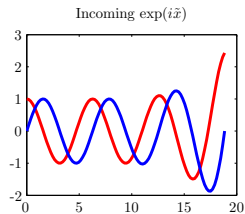
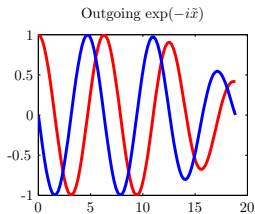
Model Problem Illustrated

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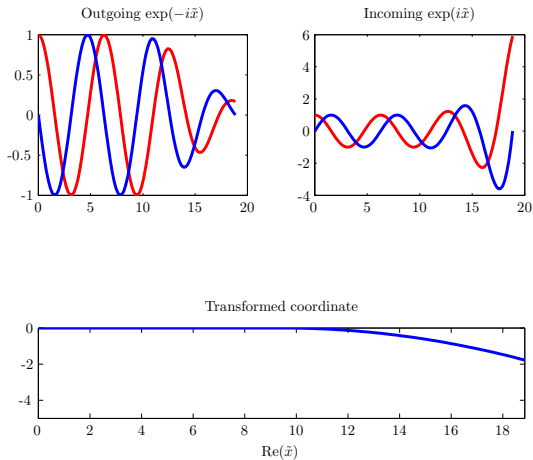
Model Problem Illustrated

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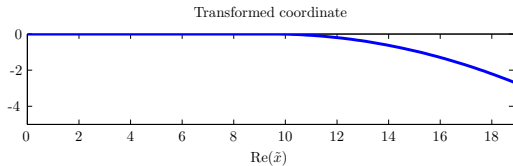
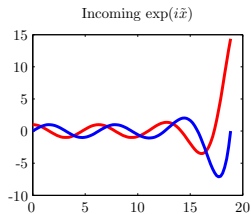
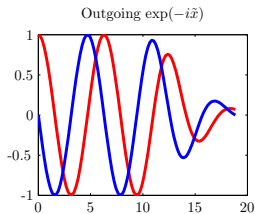
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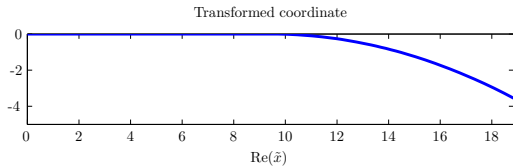
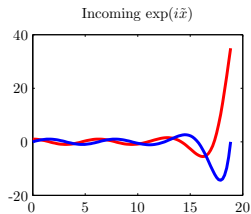
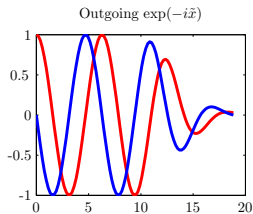
Model Problem Illustrated

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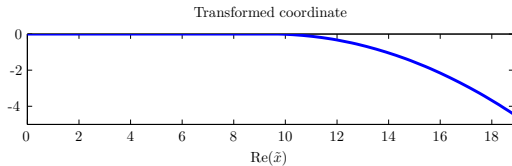
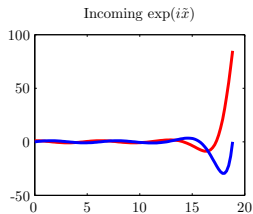
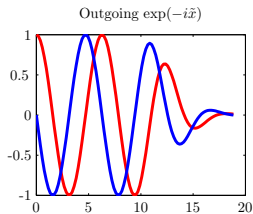
Model Problem Illustrated

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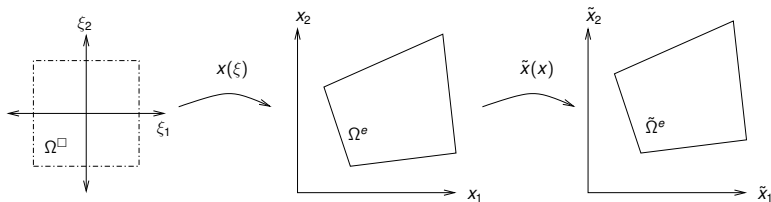
Model Problem Illustrated

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Finite Element Implementation

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- Combine PML and isoparametric mappings

$$\mathbf{k}^e = \int_{\Omega^\square} \tilde{\mathbf{B}}^T \mathbf{D} \tilde{\mathbf{B}} \tilde{J} d\Omega^\square$$

$$\mathbf{m}^e = \int_{\Omega^\square} \rho \mathbf{N}^T \mathbf{N} \tilde{J} d\Omega^\square$$

- Matrices are *complex symmetric*

Eigenvalues and Model Reduction

Want to know about the transfer function $H(\omega)$:

$$H(\omega) = p^T (K - \omega^2 M)^{-1} b$$

Can either

- Locate poles of H (eigenvalues of (K, M))
- Plot H in a frequency range (Bode plot)

Usual tactic: subspace projection

- Build an Arnoldi basis V
- Compute with much smaller V^*KV and V^*MV

Can we do better?

Variational Principles

- Variational form for complex symmetric eigenproblems:
 - Hermitian (Rayleigh quotient):

$$\rho(v) = \frac{v^* K v}{v^* M v}$$

- Complex symmetric (modified Rayleigh quotient):

$$\theta(v) = \frac{v^T K v}{v^T M v}$$

- First-order accurate eigenvectors \implies
Second-order accurate eigenvalues.
- Key: relation between left and right eigenvectors.

Accurate Model Reduction

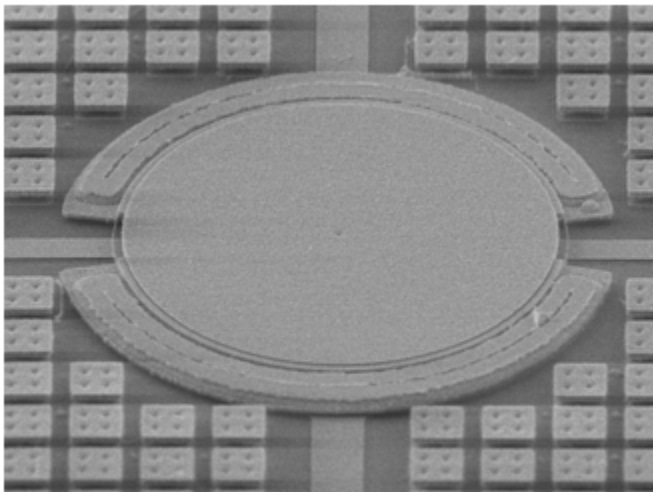
- Build new projection basis from V :

$$W = \text{orth}[\text{Re}(V), \text{Im}(V)]$$

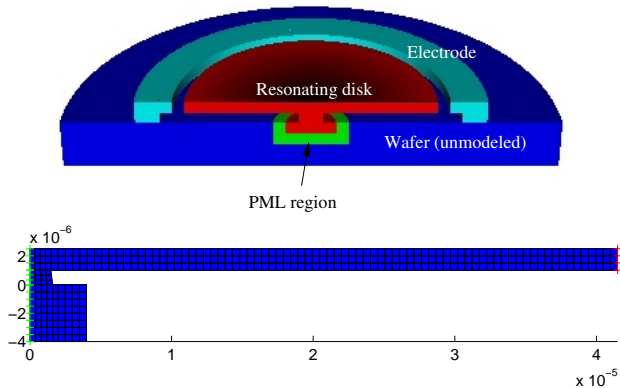
- $\text{span}(W)$ contains both \mathcal{K}_n and $\bar{\mathcal{K}}_n$
 \implies double digits correct vs. projection with V
- W is a real-valued basis
 \implies projected system is complex symmetric

Disk Resonator Simulations

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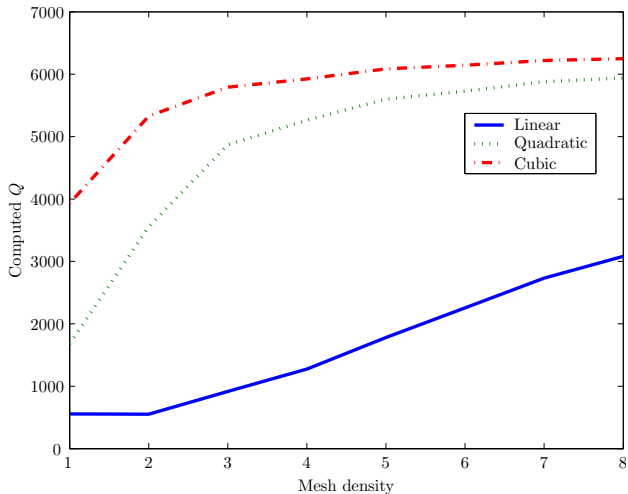
Disk Resonator Mesh



- Axisymmetric model with bicubic mesh
- About 10K nodal points in converged calculation

Mesh Convergence

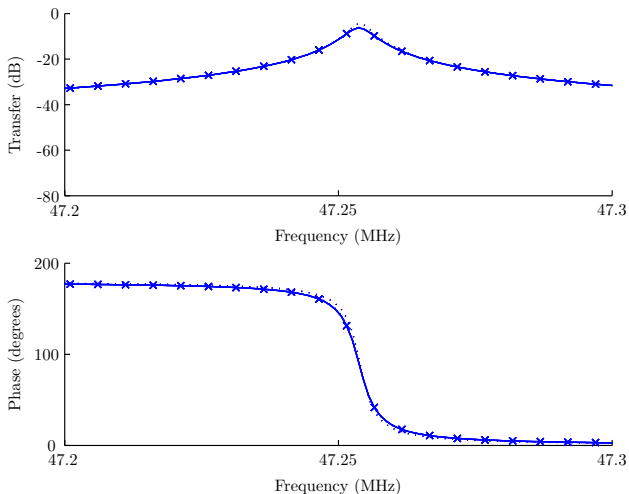
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Cubic elements converge with reasonable mesh density

Model Reduction Accuracy

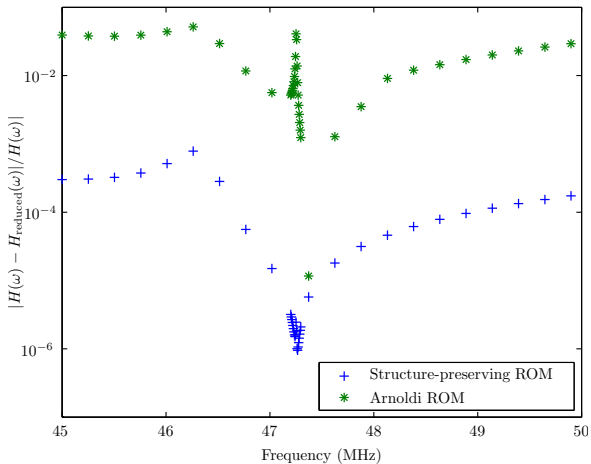
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Results from ROM (solid and dotted lines) nearly indistinguishable from full model (crosses)

Model Reduction Accuracy

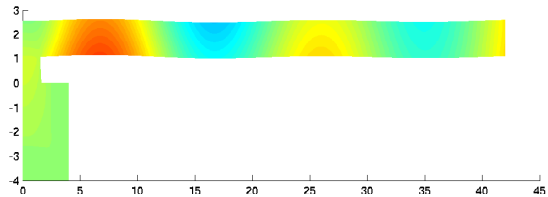
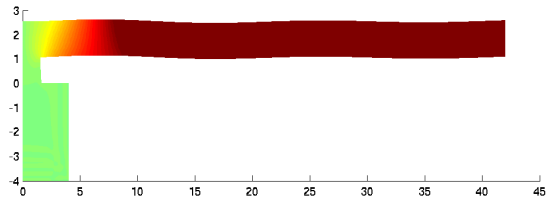
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Preserve structure \implies
get twice the correct digits

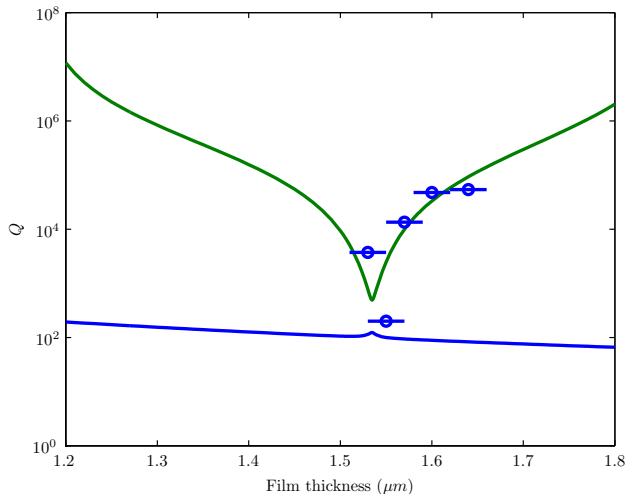
Response of the Disk Resonator

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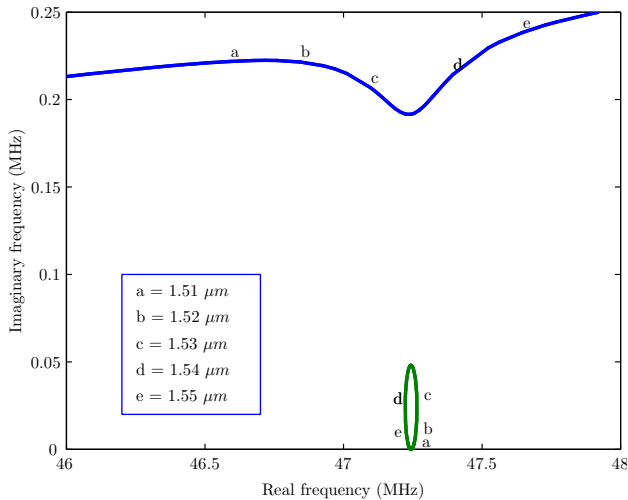
Variation in Quality of Resonance

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Simulation and lab measurements vs. disk thickness

Explanation of Q Variation



Interaction of two nearby eigenmodes

Conclusions

- RF MEMS are a great source of problems
 - Interesting applications
 - Interesting physics (and not altogether understood)
 - Interesting numerical mathematics
- See also:
 - HiQLab: simulation of resonant MEMS
www.cs.berkeley.edu/~dbindel/hiqlab/
 - Bindel and Govindjee. Elastic PMLs for resonator anchor loss simulations. *IJNME*, 64(6):789–818, October 2005.